

Supporting information

High Performance Flexible Memristor Based on Lead Free AgBiI_4

Perovskite with Ultralow Operating Voltage

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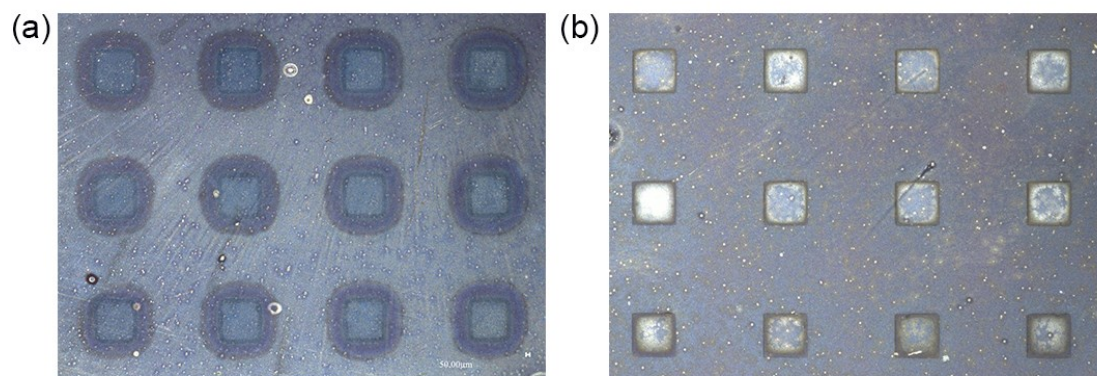


Fig. S1 (a) The photograph of device without PMMA layer. (b) The photograph of device with PMMA layer.

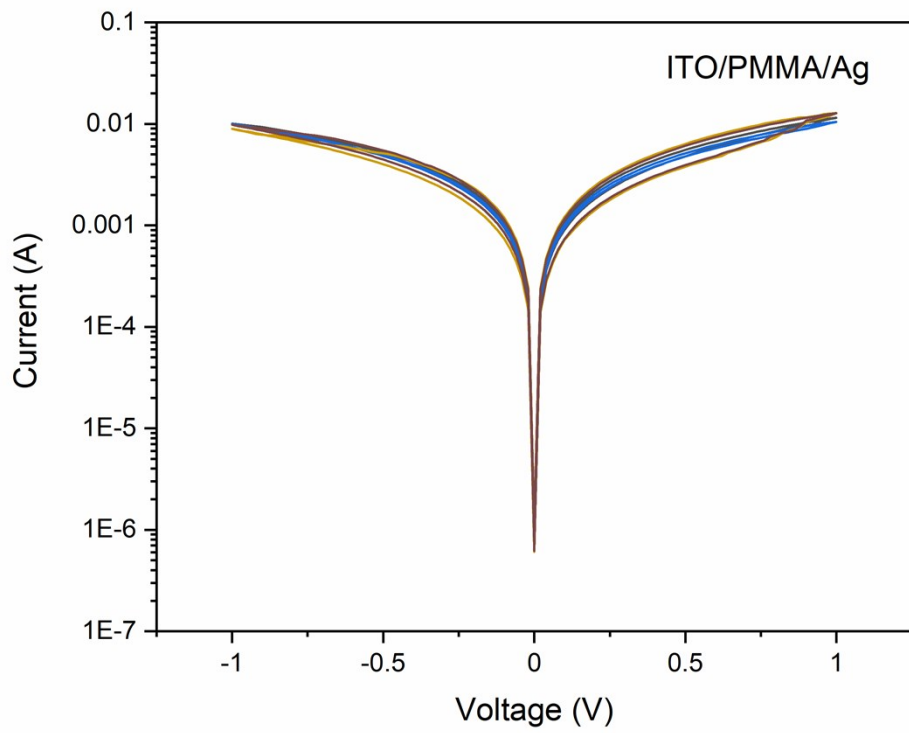


Fig. S2 The current-voltage ($I-V$) characteristics of the PMMA with a structure of ITO/PMMA/Ag.

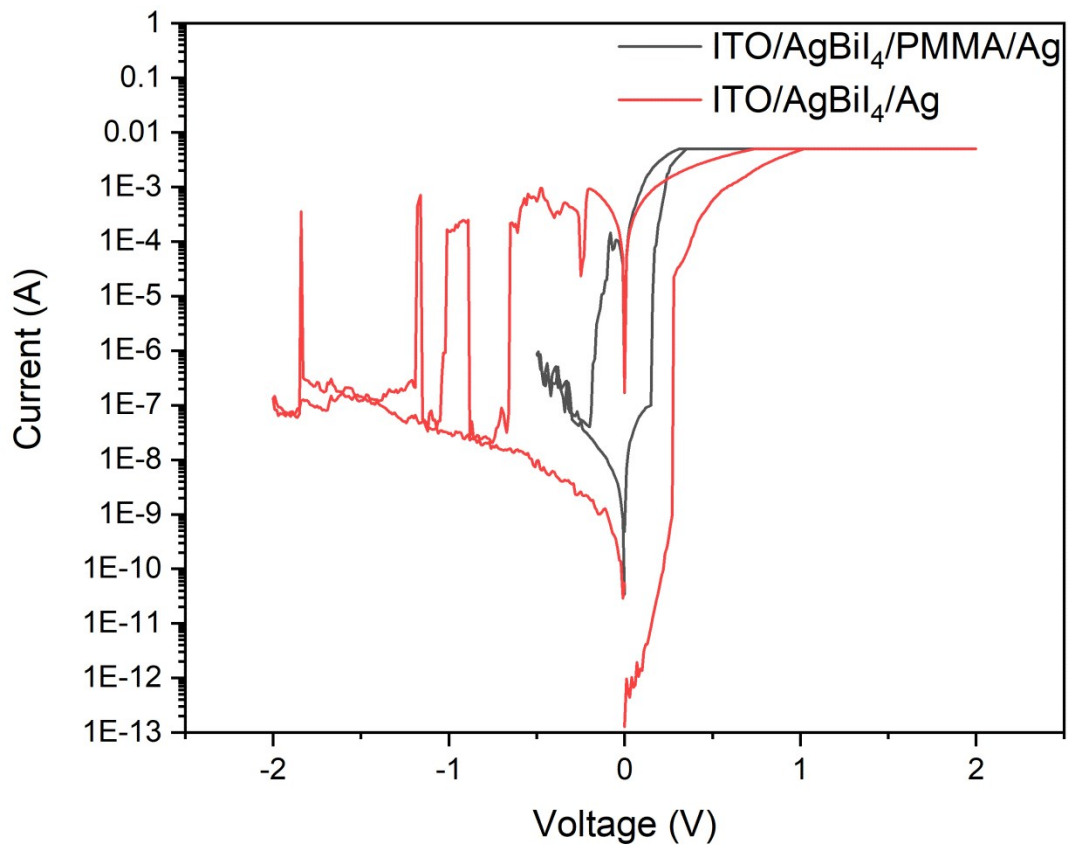


Fig. S3 The current-voltage (I - V) characteristics of the AgBiI₄ based memory devices with or without PMMA insulating layer.

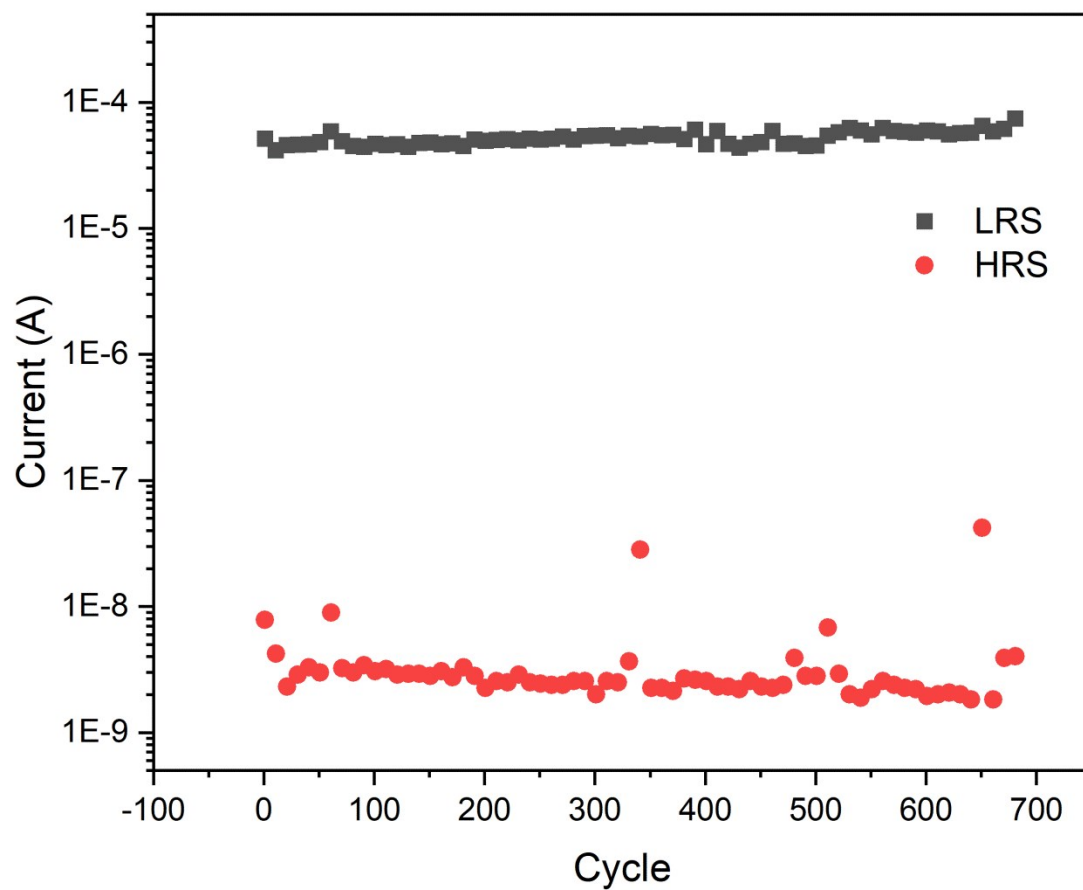


Fig. S4 The switching endurance property of the memory device.

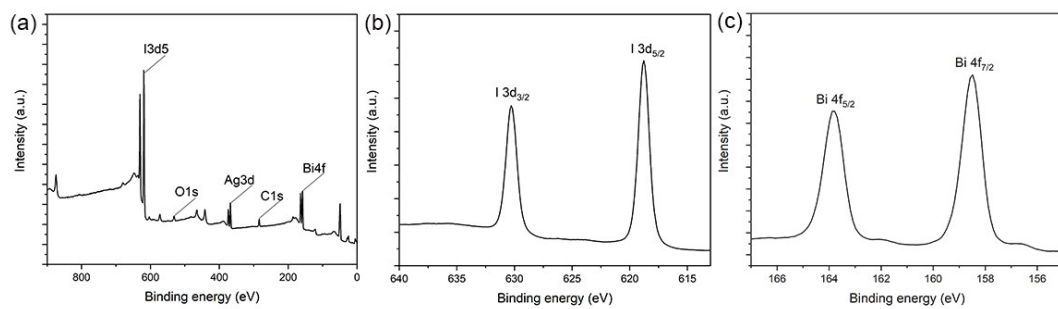


Fig. S5 The XPS survey of the AgBiI₄ film.

Table. S1 Comparison of various perovskite-based RRAM devices.

Structure	SET Voltage [V]	RESET Voltage [V]	Retention Time [s]	Stable Endurance [times]	ON/OFF ratio	Ref.
Au/CH ₃ NH ₃ PbI ₃ /ITO/PET	0.7	-0.5	10 ⁴	400	10	[16]
Au/Cs ₃ Bi ₃ I ₉ /ITO/PET	0.3	-0.5	10 ⁴	-	10 ³	[17]
Au/CH ₃ NH ₃ PbI ₃ /Pt/Ti/SiO ₂ /Si	1	-1	10 ⁵	500	10 ³	[50]
Au/CH ₃ NH ₃ PbCl _x I _{3-x} /TiO ₂ /Ti	1	-1.58	10 ⁴	-	20	[51]
Ag/CH ₃ NH ₃ PbBr _{2.54} Cl _{0.46} /FTO/glass	0.7	-1.3	10 ³	250	10 ³	[52]
Ag/CH ₃ NH ₃ PbBr ₃ /FTO/glass	3	-4	10 ³	250	10 ³	[52]
Ag/CH ₃ NH ₃ PbI _{3-x} Cl _x /FTO/glass	1.5	-1.5	4×10 ⁴	10 ³	10 ²	[53]
Au/(NH ₂ -dendrimer/oleic acid-stabilized BaTiO ₃) _n /Pt/Ti/SiO ₂ /Si	1.5	-1.8	10 ⁵	200	10 ⁴	[54]
Ag/BiMnO ₃ /Ti	3.9	-3.75	-	100	10	[55]
Au/CH ₃ NH ₃ PbI _{3-x} Cl _x /FTO/glass	0.8	-0.6	10 ⁴	100	2	[56]
Au/Ti/ZnO/Nb-doped SrTiO ₃ /Al/Au	-2	3	10 ⁴	30	10 ²	[57]
Al/CsPbBr ₃ /PEDOT:PSS/ITO/PET	-0.6	1.7	-	50	10 ²	[58]
Cu/CH ₃ NH ₃ PbI ₃ /poly(3,4-ethyl enedioxy-thiophene)-poly(styrenesulfonate)(PEDOT:PSS)/ITO/glass	-1	1.8	10 ⁴	3000	10 ⁴	[59]
Au/BaTi _{0.95} Co _{0.05} O ₃ /SrRuO ₃ /mica	12	-6	8.6×10 ⁴	3.6×10 ⁵	50	[60]
Ag/PMMA/AgBiI ₄ /ITO	0.16	-0.16	10 ⁴	700	10 ⁴	[This work]

Table. S2 Element ratios of AgBiI₄ layer from XPS survey.

Element	Atomic (%)
Ag	8.54
Bi	7.87
I	31.38